Attorney Docket No.: 989_001DIV1

PATENT

UNITED STATES PATENT AND TRADEMARK OFFICE

Inventor(s): James E. Moon et al.

Serial No.:

10/004,463

Art Unit:

1746

Filed: November 02, 2001

Examiner:

Not Yet Assigned

Title:

METHOD FOR FABRICATING MEMS AND MICROFLUDIC DEVICES

USING LATENT MASKING TECHNIQUE

Assistant Commissioner for Patents Washington, DC 20231

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail addressed to Assistant Commissioner for Patents, Washington D.C. 20231, on April 18, 2003.

Cyfithia L. Losurdo

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Sir:

Pursuant to 37 C.F.R. §1.56, Applicant submits the following Information Disclosure Statement, and directs the attention of the U.S. Patent and Trademark Office to the references listed on the attached Form PTO-1449.

The information is presented so that the U.S. Patent and Trademark Office may, in the first instance, determine any materiality thereof to the claimed invention. See 37 C.F.R. §1.104(a) and §1.105 (concerning the PTO duty to consider and use any such information).

Applicant respectfully requests that the Examiner expressly consider the information disclosed herein during the prosecution of this application, that the Examiner initial the corresponding box on the enclosed Form PTO-1449 next to each of the considered references, and that these references be made of record therein and appear among the "References Cited" on any patent which issues from this application.

This Information Disclosure Statement "shall not be construed as a representation that a search has been made." See 37 C.F.R. § 1.97(g). This Information Disclosure Statement "shall

not be construed to be an admission that the information cited in the statement is, or is considered to be, material to patentability as defined in § 1.56(b)." See 37 C.F.R. § 1.97(h).

Copies of references AG-AM are enclosed. References AN-AZ were cited in the parent application, U.S. Serial No. 09/334,408 (now U.S. Patent No. 6,444,138), and considered by the Examiner of the parent application on July 30, 2001. Therefore pursuant to 37 C.F.R. § 1.98(d) and M.P.E.P. § 609A(2), copies of References AN-AZ are not provided herewith.

The present Information Disclosure Statement is being filed (1) no later than three months from the application's filing date or (2) before the mailing date of the first Office Action on the merits (whichever is later), and therefore no certification under 37 C.F.R. §1.97(e) or fee under 37 C.F.R. §1.17(p) is required.

While no fee is believed due with this submission, the Commissioner is hereby authorized to charge any additional fees associated with this submission, or credit any overpayment, to Deposit Account No. 50-0289.

Respectfully submitted,

April 18, 2003

Date

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INFORMATION DISCLOSURE STATEMENT BY APPLICANT

989_001DIV1

Scrial No.

10/004,463

James E. Moon et al.

November 02, 2001

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	AH	5,131,978	07/21/1992	O'Neill			06/07/1990
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